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Attorney Docket No. UMC-96-279 CON  
Client Matter No. 81848.0016.001

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Serial No. 09/546,174

Application of: LIU, Chih-Chien *et al*

Filed: April 11, 2000

Art Unit: 1711

Examiner: SERGENT, R.A.

Attorney Docket No. UMC-96-279 CON

For: HIGH DENSITY PLASMA CHEMICAL  
VAPOR DEPOSITION PROCESS

Confirmation No.: 4793

Customer No.: **25235**

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**AMENDMENT AND RESPONSE UNDER 37 C.F.R. § 1.113**

Mail Stop AF  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

A final Office Action was mailed in the above case June 4, 2003. Please reconsider the case in light of the following remarks.

**Amendments to the Claims** are reflected in the listing of claims, which begins on page 2 of this paper.

**Remarks** begin on page 9 of this paper.